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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

Sang H. Ahn et al. Applicants

November 28, 2003 Filing Date

<u>Unknown</u> Group

U. S. PATENT DOCUMENTS							
Examiner Initial	Document Number	Issue <u>Date</u>	<u>Name</u>	Class	Subclass	Filing Date If Appropriate	
<u> Mo</u>	6,171,764	01/09/01	Ku et al.	430	322		
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FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Publication <u>Date</u>	Name	Class	Subclass	Translation If Appropriate
wo	EP 1011135	06/21/00	Hsia et al.	H01L	21/768	
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